### APPENDIX E

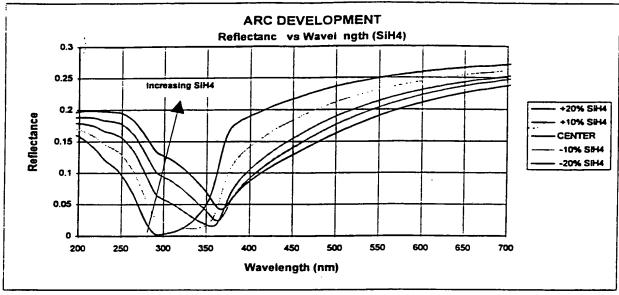
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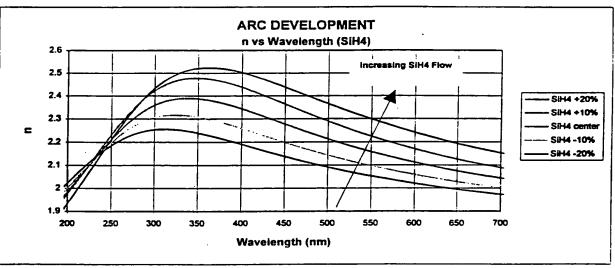
## ARL Film RBS/HFS Sample Results

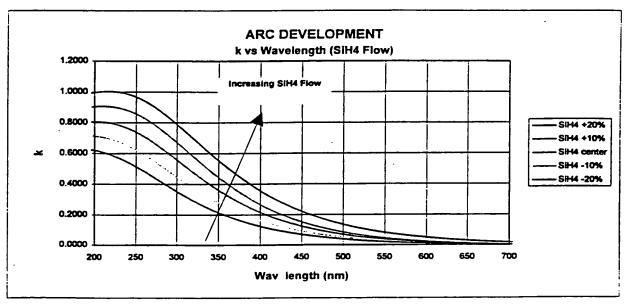
Process	DEEP-UV	DEEP-UV	DEEP-UV	DEEP-UV	DEEP-UV	I-LINE	I-LINE	I-LINE
	[w/NH <sub>3</sub> ]	[w/o NH <sub>3</sub> ]	[+60% SiH <sup>4</sup> ]	[Standard]	[-40% SiH4]	[300C dep]	[400C dep]	[w/o W <sub>2</sub> ]
Faceplate	△ Nitride	Δ Nitride	Δ Nitride	Nitride A Nitride A Nitride A Nitride Nit	△ Nitride	GG Nitride	GG Nitride	GG Nitride
Pumping Plate		Δ Nitride	Δ Nitride		Δ Nitride	5-hole	5-hole	13-hole
Blocker	Std. w/cntr holes	Std. w/cntr holes	Standard	Standard	Standard	Standard	Standard	Standard
Temperature(°C)	350	350	350	350	350	300	400	350
Pressure(torr)	4.6	4.6	4.6	4.6	4.6	5.3	5.3	5.0
Spacing(mils)	200	200	200	200	200	525	525	460
RF1 (watts)	160	091	160	160	160	130	130	1 <b>50</b>
SiH <sub>4</sub> (sccm)	51	51	81	51	20	63	63	82
N <sub>2</sub> O (sccm)	30	155	30	30	30	34	34	06
N <sub>2</sub> (sccm)	200	200	200	200	200	200	200	0
He (sccm)	2200	2200	2000	2000	2000	1900	1900	2200
NH <sub>3</sub> (sccm)	125	i	1		•			
Thickness	700A	1200A	300A	300A	300A	300A	300A	300
c	2.3	1.8		2.1		2.5	2.65	2.5
א	0.3	0.14		7.0		0.42	0.63	0.39
% reflectance	1.10%	1.80%		15%		4.000%	800.6	2.5%
Atomic conc.(%)								
н	15.0%	13.5%	17.0%	16.0%	14.0%	20.0%	13.0%	8.0%
ပ	%0.0	%0.0	10.0%	5.0%	.0.0%	8.0%	10.0%	0.00%
z	34.0%	15.0%	15.3%	18.1%	15.0%	17.0%	17.0%	10.0%
0	80.6	34.5%	15.7%	15.9%	31.0%	15.0%	15.0%	20.0%
S.	42.0%	37.0%	42.0%	45.0%	40.0%	40.0%	45.0%	52.0%

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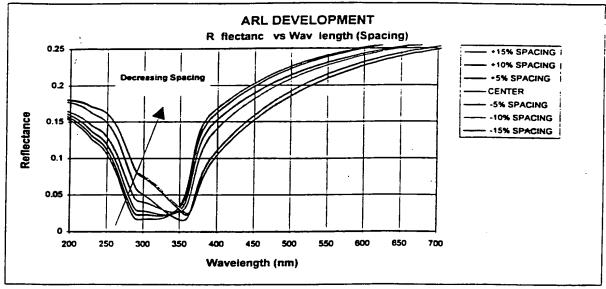


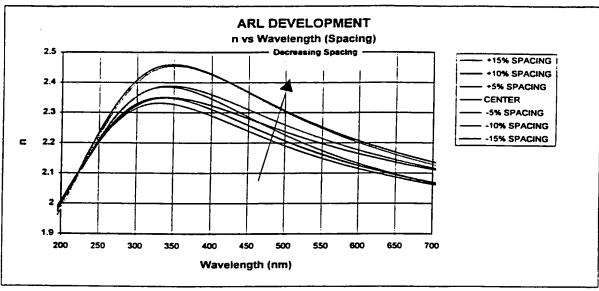


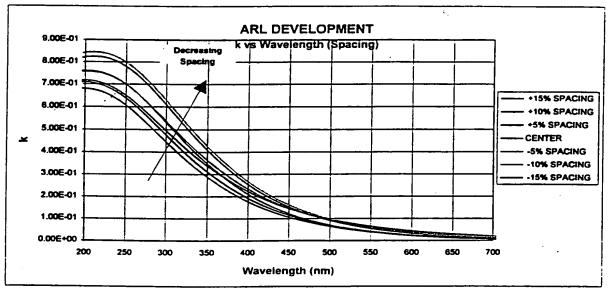






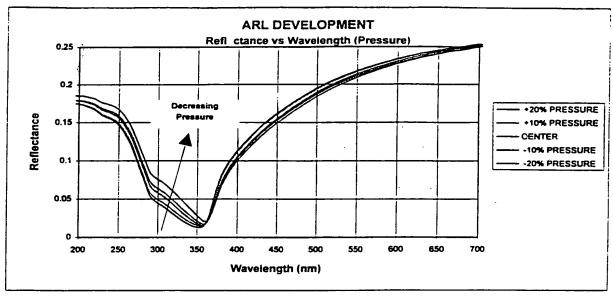


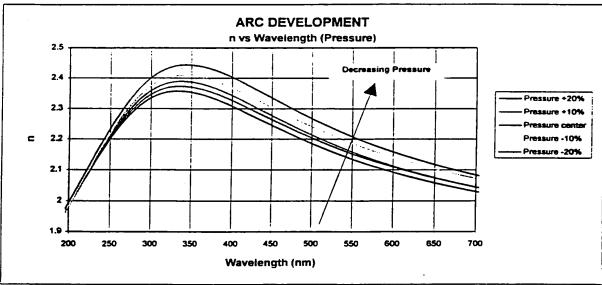


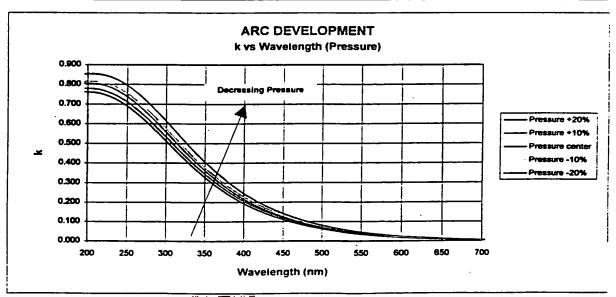


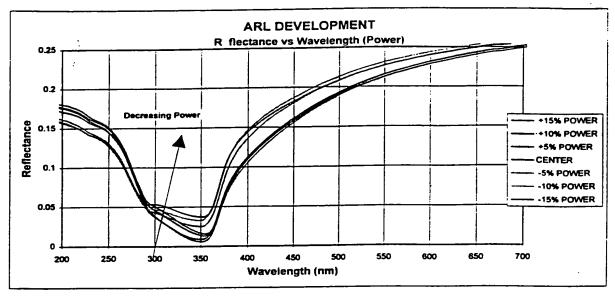
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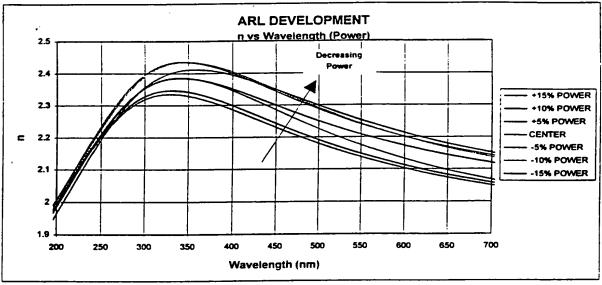


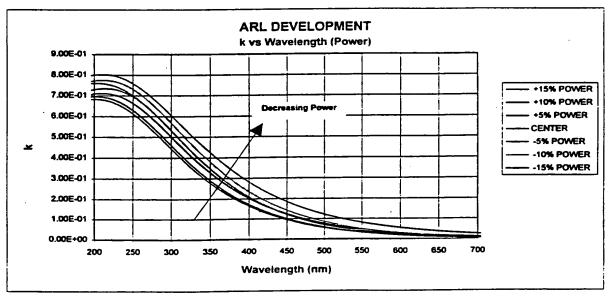


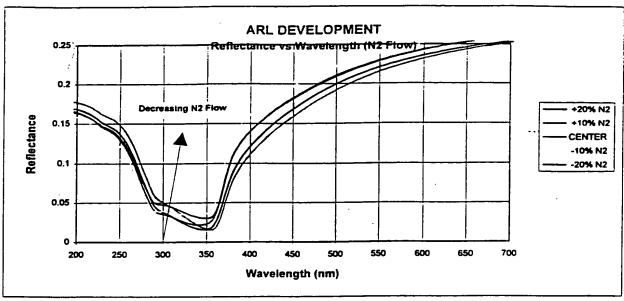


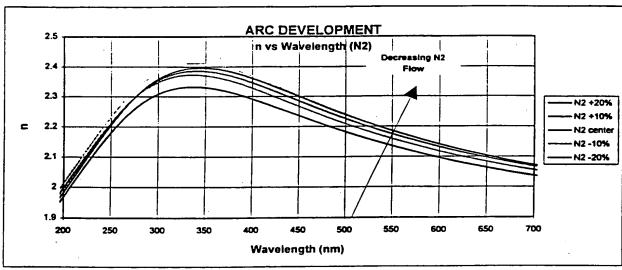


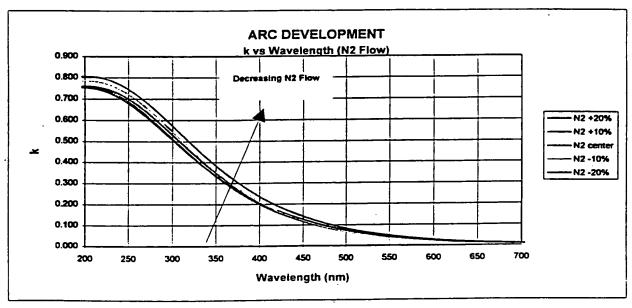






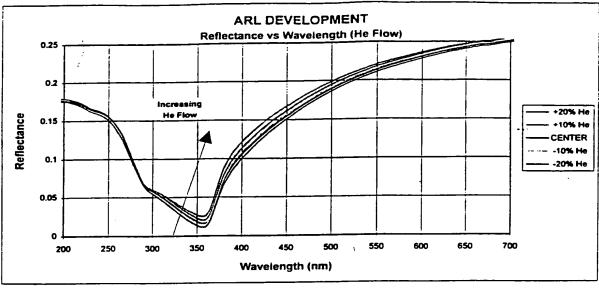


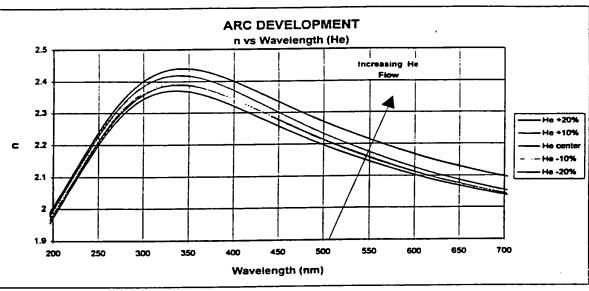


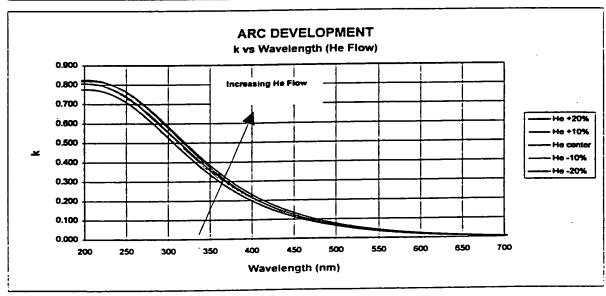


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